

ABSTRACT

MEMS and microelectronic devices and fabrication methods feature providing a first material including a glass, providing a second material having an elastic modulus greater than the elastic modulus of silicon, causing the second material to have a surface with a RMS surface roughness of greater than $0.001\text{ }\mu\text{m}$ and less than

5 approximately $0.15\text{ }\mu\text{m}$, contacting the surface of the second material to a surface of the first material, and applying a voltage between the first and second materials to cause an anodic bond to form.

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